

L Number	Hits	Search Text	DB	Time stamp
1	219	SEM and objective adj lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5)	USPAT; EPO; JPO; DERWENT	2004/03/11 08:59
4	0	((SEM and objective adj lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5)) and 250/\$.ccls.) and auger) and sheild	USPAT; EPO; JPO; DERWENT	2004/03/11 08:51
5	10	((SEM and objective adj lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5)) and 250/\$.ccls.) and auger) and shield	USPAT; EPO; JPO; DERWENT	2004/03/11 08:51
2	190	(SEM and objective adj lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5)) and 250/\$.ccls.	USPAT; EPO; JPO; DERWENT	2004/03/11 09:03
6	6	SEM and lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5) and secondary adj optical	USPAT; EPO; JPO; DERWENT	2004/03/11 09:26
7	0	(SEM and lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5) and secondary adj optical) and auger	USPAT; EPO; JPO; DERWENT	2004/03/11 08:59
3	27	((SEM and objective adj lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5)) and 250/\$.ccls.) and auger	USPAT; EPO; JPO; DERWENT	2004/03/11 08:59
8	48	((SEM and objective adj lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5)) and 250/\$.ccls.) and shield\$5	USPAT; EPO; JPO; DERWENT	2004/03/11 09:04
9	52	SEM and lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5) and auger	USPAT; EPO; JPO; DERWENT	2004/03/11 09:26
10	0	(SEM and lens and beam and secondary adj electron and deflect\$5 and (detect\$5 analyz\$5) and auger) and virtual same auger	USPAT; EPO; JPO; DERWENT	2004/03/11 09:26
-	33	SEM and objective adj lens and beam and secondary adj electron and auger	USPAT; EPO; JPO; DERWENT	2004/03/11 08:50
-	26	(SEM and objective adj lens and beam and secondary adj electron and auger) and analy\$6	USPAT; EPO; JPO; DERWENT	2003/10/17 13:55
-	10	((SEM and objective adj lens and beam and secondary adj electron and auger) and analy\$6) and shield	USPAT; EPO; JPO; DERWENT	2003/10/17 11:34
-	20	((SEM and objective adj lens and beam and secondary adj electron and auger) and analy\$6) and resolution	USPAT; EPO; JPO; DERWENT	2003/10/17 14:00
-	9	((SEM and objective adj lens and beam and secondary adj electron and auger) and analy\$6) and magnetic adj field	USPAT; EPO; JPO; DERWENT	2003/10/17 14:00
-	1	(SEM and objective adj lens and beam and secondary adj electron and auger) and capacitor same image	USPAT; EPO; JPO; DERWENT	2003/10/17 14:36
-	38	SEM and objective adj lens and beam and auger	USPAT; EPO; JPO; DERWENT	2003/10/17 14:36
-	1	(SEM and objective adj lens and beam and auger) and capacitor same image	USPAT; EPO; JPO; DERWENT	2003/10/17 14:58
-	1	(SEM and objective adj lens and beam and auger) and electrostatic adj capacitor	USPAT; EPO; JPO; DERWENT	2003/10/17 14:59
-	18	(SEM and objective adj lens and beam and auger) and electrostatic	USPAT; EPO; JPO; DERWENT	2003/10/17 14:59
-	123	((scanning adj electron adj microscope) SEM) and Auger and optic\$5 and lens and (detect\$5 analyz\$5)	USPAT; EPO; JPO; DERWENT	2004/03/10 15:25